



Mr. Hisashi Kitami

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Mr. Hisashi Kitami has been working for Sumitomo Heavy Industries, Ltd. in Japan since 2011. He received B.E. and M.E. degrees from Tottori University, Japan, both in Engineering, in 2009 and in 2011. His main engagement is R&D of reactive plasma deposition with direct current (dc) arc discharge (RPD). On the basis of the analysis of the data determined by plasma diagnostics measurements using a mass energy analyzer combined with the Langmuir probe method, he has also clarified the features of the arc-plasma based deposition technology. He has also been elucidating the characteristics of the thin films produced by RPD. Based on the results, he has been proposing the advantages of RPD over the other deposition methods in the view points of the industrial process. He has recently developed and proceed in the business of the devices with the irradiation of negatively charged ions of elements such as hydrogen and oxygen species using the above plasma technology.